2 2 2003 Elicket No.: 1268-093A PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Moshe FINAROV : Confirmation No. 8657

U.S. Patent Application No. 09/626,793 : Group Art Unit: 2851

Filed: July 26, 2000 : Examiner: D. Esplin

For: APPARATUS FOR INTEGRATED MONITORING OF WAFERS AND FOR

PROCESS CONTROL IN THE SEMICONDUCTOR MANUFACTURING AND A

METHOD FOR USE THEREOF

## REQUEST FOR CORRECTED FILING RECEIPT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Attached is a copy of the Official Filing Receipt received from the U.S. Patent and Trademark Office in the above-referenced application, on which we noticed that the following information has been omitted:

1) Foreign Application: Israel Application No. 126949, filed November 8, 1998

2) Domestic Priority: PCT/IL99/00598, filed November 7, 1999

A copy of the Declaration as filed is also attached. It is requested that a corrected filing receipt be issued.

Respectfully submitted,

LOWE WAYPTMAN GILMAN & BERNER, LLP

Bergamin J. Hauptman Registration No. 29,310

1700 Diagonal Road, Fuite 300 Alexandria, Virginia 22314 703-684-1111 BJH/klb Facsimile: 703-518-5499

Date: September 16, 2003



TES PATENT AND TRADEMARK OFFICE

COMMISSIONER FOR PATENTS UNITED STATES PATENT AND TRADEMARK OFFICE WASHINGTON, D.C. 20231 www.uspto.gov

GRP ART UNIT | FIL FEE REC'D | ATTY.DOCKET.NO | DRAWINGS | TOT CLAIMS | IND CLAIMS APPLICATION NUMBER FILING DATE 09/626,793 07/26/2000 1268-093A

**CONFIRMATION NO. 8657** 

**FILING RECEIPT** 

Lowe Hauptman Gopstein Gilman & Berner LLP Suite 310 1700 Diagonal Road Alexandria, VA 22314

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Date Mailed: 01/22/2001

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the PTO processes the reply to the Notice, the PTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Moshe Finarov, Rehovot, ISRAEL;

Continuing Data as Claimed by Applicant

THIS APPLICATION IS A CIP OF 09/509,080 05/22/2000

Foreign Applications

If Required, Foreign Filing License Granted 09/18/2000

**Projected Publication Date:** 

Non-Publication Request: No

Early Publication Request: No

\*\* SMALL ENTITY \*\*

Title

Apparatus for integrated monitoring of wafers and for process control in the semiconductor manufacturing and a method for use thereof

**Preliminary Class** 

359

Data entry by : SCOTT, JOSEPH

Team : OIPE

Date: 01/22/2001

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